

**AP20 Rec'd PCT/PTO 08 MAR 2006**

<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT PTO FORM 1449</b>	Atty. Docket No. 10191/4346	Serial No. To Be Assigned  <b>10/571246</b>
	Applicant(s) Joachim RUDHARD	
	Filing Date Herewith	Group To Be Assigned

**U. S. PATENT DOCUMENTS**

EXAMINER'S INITIALS	PATENT NUMBER	PATENT DATE	NAME	CLASS	SUBCLASS	FILING DATE
	6,198,098*	March 6, 2001	Laou			
	6,210,988*	April 3, 2001	Franke et al.			

**FOREIGN PATENT DOCUMENTS**

EXAMINER'S INITIALS	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION	
						YES	NO

**OTHER DOCUMENTS**

EXAMINER'S INITIALS	AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.	
	<del>Tillack B. et al; MONITORING OF DEPOSITION AND DRY ETCHING OF SI/SIGE MULTIPLE STACKS; Journal of Vacuum Science And Technology: Part B, American Institute Of Physics, New York, US.*</del>	
	<del>Premachandran C S et al; A NOVEL ELECTRICALLY CONDUCTIVE WAFER THROUGH HOLD FILLED VIAS INTERCONNECT FOR 3D MEMS PACKAGING; 2003 Proceedings 33rd Electronic Components And Technology Conference.*</del>	
EXAMINER	/Ming Hung Hung/	DATE CONSIDERED 04/29/2008
EXAMINER: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.		

\*Copy of reference is not enclosed because reference is cited in Search Report (copy of reference provided by International Searching Authority).

ALL REFERENCES CONSIDERED EXCEPT WHERE LINED THROUGH. /M.H./